L Number	Hits	Search Text	DB	Time stamp
1	67	(ghoshal cordes dimilia doyle speidell).in. and thermoelectric	USPAT;	2003/06/19 11:31
			US-PGPUB;	
			EPO; JPO; DERWENT;	
			IBM_TDB	
8	285	438/20.ccls.	USPAT;	2003/06/19 11:31
			US-PGPUB;	
			EPO; JPO;	
		·	DERWENT;	
45	215	438/20.ccls, and (metal or copper or cu)	IBM_TDB USPAT;	2003/06/19 11:34
15	215	438/20.ccis. and (metal of copper of cu)	US-PGPUB;	2000/00/10 11:04
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	2002/06/40 11:27
22	69	438/20.ccls. and ((metal or copper or cu) near15 (mask resist	USPAT; US-PGPUB;	2003/06/19 11:37
		photoresist pattern\$3))	EPO; JPO;	
			DERWENT:	
			IBM_TDB	
29	101	438/20.ccls. and ((conductive conducting) near15 (mask resist	USPAT;	2003/06/19 11:35
		photoresist pattern\$3))	US-PGPUB;	
			EPO; JPO;	
			DERWENT; IBM_TDB	
36	144	(438/20.ccls. and ((metal or copper or cu) near15 (mask resist	USPAT;	2003/06/19 11:36
30	177	photoresist pattern\$3))) (438/20.ccls. and ((conductive	US-PGPUB;	
		conducting) near15 (mask resist photoresist pattern\$3)))	EPO; JPO;	
			DERWENT;	
			IBM_TDB USPAT;	2003/06/19 11:37
43	106	((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive	US-PGPUB;	2003/00/19 11.37
		conducting) near15 (mask resist photoresist pattern\$3)))) and	EPO; JPO;	
		@ad<20001130	DERWENT;	
			IBM_TDB	
50	106	((438/20.ccls. and ((metal or copper or cu) near15 (mask resist	USPAT;	2003/06/19 11:38
		photoresist pattern\$3))) (438/20.ccls. and ((conductive	US-PGPUB; EPO; JPO;	
		conducting) near15 (mask resist photoresist pattern\$3)))) and @ad<20001207	DERWENT;	
		@au	IBM_TDB	
57	56	((438/20.ccls. and ((metal or copper or cu) near15 (mask resist	USPAT;	2003/06/19 11:37
		photoresist pattern\$3))) (438/20.ccls. and ((conductive	US-PGPUB;	
		conducting) near15 (mask resist photoresist pattern\$3)))) and	EPO; JPO;	
		@rlad<20001207	DERWENT; IBM_TDB	
64	128	(((438/20.ccls. and ((metal or copper or cu) near15 (mask	USPAT;	2003/06/19 11:37
5,	120	resist photoresist pattern\$3))) (438/20.ccls. and ((conductive	US-PGPUB;	
		conducting) near15 (mask resist photoresist pattern\$3)))) and	EPO; JPO;	
		@ad<20001207) (((438/20.ccls. and ((metal or copper or cu)	DERWENT;	
		near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and	IBM_TDB	
		((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and @rlad<20001207)		
71	137	438/20.ccls. and ((metal or copper or Cu or conducting or	USPAT;	2003/06/19 11:38
• •		conductive) near15 etch\$3)	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
70	445	((438/20.ccls. and ((metal or copper or cu) near15 (mask resist	IBM_TDB USPAT;	2003/06/19 11:38
78	115	photoresist pattern\$3))) (438/20.ccls. and ((conductive	US-PGPUB;	
		conducting) near15 (mask resist photoresist pattern\$3)))) and	EPO; JPO;	
		(438/20.ccls. and ((metal or copper or Cu or conducting or	DERWENT;	
		conductive) near15 etch\$3))	IBM_TDB	2002/06/40 44:02
85	84		USPAT; US-PGPUB;	2003/06/19 14:03
		resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and	EPO; JPO;	
		(438/20.ccls. and ((metal or copper or Cu or conducting or	DERWENT;	
		conductive) near15 etch\$3))) and @ad<20001207	IBM_TDB	

		W 100 100 1 1 // w 1 1	LICDAT	0000/00/40 44 00
92	47	(((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and (438/20.ccls. and ((metal or copper or Cu or conducting or conductive) near15 etch\$3))) and @rlad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:38
99	104	((((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and (438/20.ccls. and ((metal or copper or Cu or conducting or conductive) near15 etch\$3))) and @ad<20001207) ((((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3)))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and (438/20.ccls. and ((metal or copper or Cu or conducting or conductive) near15 etch\$3))) and @rlad<20001207)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:42
106	99	(((((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3))) and (438/20.ccls. and ((metal or copper or Cu or conducting or conductive) near15 etch\$3))) and @ad<20001207) ((((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and (438/20.ccls. and ((metal or copper or Cu or conducting or conductive) near15 etch\$3))) and @rlad<20001207)) and (point tip)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:43
113	72	(((((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and (438/20.ccls. and ((metal or copper or Cu or conducting or conductive) near15 etch\$3))) and @ad<20001207) ((((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and (438/20.ccls. and ((metal or copper or Cu or conducting or conductive) near15 etch\$3))) and @rlad<20001207)) and	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 14:00
120	1286	(point tip) near15 (metal copper Cu conductive conducting) (point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/06/19 14:45
127	232	((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 14:48
134	201	(((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/06/19 14:48
141	55	(((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 14:03
148	212	((((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) ((((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 14:37
155	0	(((((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) ((((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207)) and (peltier thermoelectric thermo-electric cooler)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 16:44

162	0	(((((point tip needle) near12 ((metal copper Cu conductive	USPAT;	2003/06/19 14:38
	1	conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) ((((point tip needle) near12 ((metal copper	US-PGPUB; EPO; JPO;	
		Cu conductive conducting) near3 etch\$3)) same (resist	DERWENT;	
		photoresist)) and @rlad<20001207)) and (seeb?ck)	IBM_TDB	
169	1490	(point tip tipped needle cone pointed conical conically conicly	USPAT;	2003/06/19 14:47
100		pyramid pyramidal pyramidally sharp) near12 ((metal copper	US-PGPUB;	
		Cu conductive conducting) near3 etch\$3)	EPO; JPO;	
			DERWENT;	
			IBM_TDB	000000000000000000000000000000000000000
176	266	((point tip tipped needle cone pointed conical conically conicly	USPAT;	2003/06/19 14:48
		pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist	US-PGPUB; EPO; JPO;	
		photoresist)	DERWENT;	
,		protorcolory	IBM TDB	
183	223	(((point tip tipped needle cone pointed conical conically	USPAT;	2003/06/19 17:28
		conicly pyramid pyramidal pyramidally sharp) near12 ((metal	US-PGPUB;	
		copper Cu conductive conducting) near3 etch\$3)) same (resist	EPO; JPO;	
		photoresist)) and @ad<20001207	DERWENT;	
		// /	IBM_TDB	2003/06/19 14:48
190	59	(((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal	USPAT; US-PGPUB;	2000/00/18 14.40
		copper Cu conductive conducting) near3 etch\$3)) same (resist	EPO; JPO;	
		photoresist)) and @rlad<20001207	DERWENT;	
		,	IBM_TDB	
197	234	((((point tip tipped needle cone pointed conical conically	USPAT;	2003/06/19 16:44
		conicly pyramid pyramidal pyramidally sharp) near12 ((metal	US-PGPUB;	
	!	copper Cu conductive conducting) near3 etch\$3)) same (resist	EPO; JPO; DERWENT;	
		photoresist)) and @ad<20001207) ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal	IBM TDB	
		pyramidally sharp) near12 ((metal copper Cu conductive	10100	
		conducting) near3 etch\$3)) same (resist photoresist)) and		
		@rlad<20001207)		
204	876	(peltier thermoelectric thermo-electric) and ((point pointed	USPAT;	2003/06/19 16:48
		projection tip pointy needle tipped cone conical conically	US-PGPUB;	
		conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu	EPO; JPO; DERWENT;	
		copper Al aluminum))	IBM TDB	
211	652	(peltier thermoelectric thermo-electric) and ((point pointed	USPAT;	2003/06/19 17:26
- ' '		projection tip pointy needle tipped cone conical conically	US-PGPUB;	
		conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu	EPO; JPO;	
		copper))	DERWENT;	
		1	IBM_TDB	2002/06/40 46:56
218	329	(peltier ((thermoelectric thermo-electric) adj cool\$3)) and	USPAT; US-PGPUB;	2003/06/19 16:56
		((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5	EPO; JPO;	
		(metal Cu copper))	DERWENT;	
		,	IBM_TDB	
225	171	((peltier thermoelectric thermo-electric) adj2 cool\$3) and	USPAT;	2003/06/19 17:19
		((point pointed projection tip pointy needle tipped cone conical	US-PGPUB;	
		conically conicity pyramid pyramidal pyramidally sharp) near5	EPO; JPO; DERWENT;	
		(metal Cu copper))	IBM_TDB	
232	27	((peltier thermoelectric thermo-electric) adj2 cool\$3).ti,ab. and	USPAT;	2003/06/19 17:25
202	-	((point pointed projection tip pointy needle tipped cone conical	US-PGPUB;	
		conically conicly pyramid pyramidal pyramidally sharp) near5	EPO; JPO;	
		(metal Cu copper))	DERWENT;	
			IBM_TDB	2002/00/40 47:05
239	12123	136/\$.ccls.	USPAT; US-PGPUB;	2003/06/19 17:25
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
246	347	136/\$.ccls. and ((point pointed projection tip pointy needle	USPAT;	2003/06/19 18:09
		tipped cone conical conically conicly pyramid pyramidal	US-PGPUB;	
		pyramidally sharp) near5 (metal Cu copper))	EPO; JPO;	
			DERWENT;	
L			םטו _ועםו	<u> </u>

253	346	(136/\$.ccls. and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper))) not (((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidall pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 17:27
260	306	((136/\$.ccls. and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper))) not (((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207)))) and @ad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 18:16
267	70	((136/\$.ccls. and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper))) not (((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207))) and @rlad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 17:28
274	314	(((136/\$.ccls. and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper))) not (((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207))) and @ad<20001207) (((136/\$.ccls. and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper))) not (((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207))) and @rlad<20001207)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 17:43
281	629	136/203,205.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 17:46
288	23	136/203,205.ccls. and etch\$3 and (resist photoresist)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 17:46

302	2047	etch\$3 near12 ((point pointed projection tip pointy needle	USPAT;	2003/06/19 18:15
		tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))	US-PGPUB; EPO; JPO; DERWENT;	
309	235	(etch\$3 near12 ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))) near15 (resist photoresist)	IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT;	2003/06/19 18:16
316	775	etch\$3 near12 ((pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))	IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 18:15
323	81	(etch\$3 near12 ((pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))) near15 (resist photoresist)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/06/19 18:16
330	68	((etch\$3 near12 ((pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))) near15 (resist photoresist)) and @ad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 18:16
337	11	((etch\$3 near12 ((pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))) near15 (resist photoresist)) and @rlad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/06/19 18:16
344	68	(((etch\$3 near12 ((pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))) near15 (resist photoresist)) and @ad<20001207) (((etch\$3 near12 ((pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))) near15 (resist photoresist)) and @rlad<20001207)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 18:16